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IAP20RaccPCTM10 25 MAY 2006

SHIGA7.051APC

PATENT

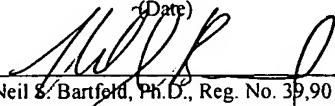
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Takeshita et al.
Appl. No. : U.S. National Phase of
PCT/JP2004/017405
Filed : Herewith
For : POSITIVE RESIST
COMPOSITION AND METHOD
FOR FORMING RESIST
PATTERN
Examiner : Unassigned
Group Art Unit : Unknown

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all
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May 25, 2006

(Date)

Neil S. Bartfeld, Ph.D., Reg. No. 39,901

PRELIMINARY AMENDMENT

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Prior to examination of the above-referenced application, please enter the following
amendments:

Amendments to the Specification begin on page 2 of this paper.

Remarks begin on page 3 of this paper.